

IAP11 Rec'd PCT/PTO 17 AUG 2006

XA-10625  
PATENT APPLICATION

## IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re the Application of:

TERANO, Akihisa et al.

Intl. Appln. No.: PCT/JP2004/011219

Intl. Filing Date: 29 July 2004

For: CAPACITANCE TYPE MEMS DEVICE, MANUFACTURING METHOD  
THEREOF, AND HIGH FREQUENCY DEVICEINFORMATION DISCLOSURE STATEMENTCommissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450Attn: Mail Stop PCT, DO/EO/US

Sir:

Pursuant to 37 C.F.R. § 1.56, and without any assertion as to materiality or prior art effect, the documents listed on the attached Form PTO-1449 are hereby cited.

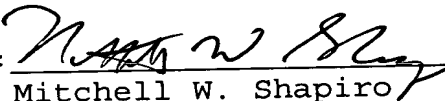
Documents AO and AP on the attached List were cited in the specification, on pages 1-3, 9 and 12, and their relevance is indicated therein. Documents AB-AE and AF-AI were cited in the International Search Report (copy attached).

Respectfully submitted,

MWS:sjk

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August 17, 2006

FORM PTO-1449				Atty. Docket No.		Appln. No.	
INFORMATION DISCLOSURE STATEMENT LIST OF DOCUMENTS CITED BY APPLICANTS				XA-10625			
				Applicant TERANO, Akihisa et al.			
				Filing Date HEREWITH		Group	
U.S. PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Name	Class	Sub-class	Filing Date
	AA	2005/0099252	05/12/05	Isobe et al.	335	78	
	AB	6,433,657	08/13/02	Chen	333	262	
	AC	6,307,452	10/23/01	Sun	333	262	
	AD	2001/0022541	09/20/01	Kasai et al.	333	105	
	AE	2004/0113715	06/17/04	Stokes et al.	333	105	
FOREIGN PATENT DOCUMENTS							
Examiner Initial		Document Number	Date	Country	Class	Sub-class	Translation
	AF	2005-142982	06/02/05	Japan (corrs. to Doc. AA)			Abstract
	AG	2000-149750	05/30/00	Japan			Abstract
	AH	2001-143595	05/25/01	Japan			Abstract
	AI	2001-266727	09/28/01	Japan			Abstract
	AJ	2004-201318	07/15/04	Japan			Abstract
	AK						
	AL						
	AM						
	AN						
OTHER (including author, title, date, pertinent pages, etc.)							
	AO	J. Yao, "Topical Review: RF MEMS from a Device Perspective," J. Micromech. Microeng. 10, 2000, pages R9-R38.					
	AP	X. Rottenberg et al., "RF-MEMS Metal Contact Capacitive Switches," 4 <sup>th</sup> Round Table on MNT for Space, May 2000, pp. 1-11.					
Examiner				Date Considered			
EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to Applicant.							